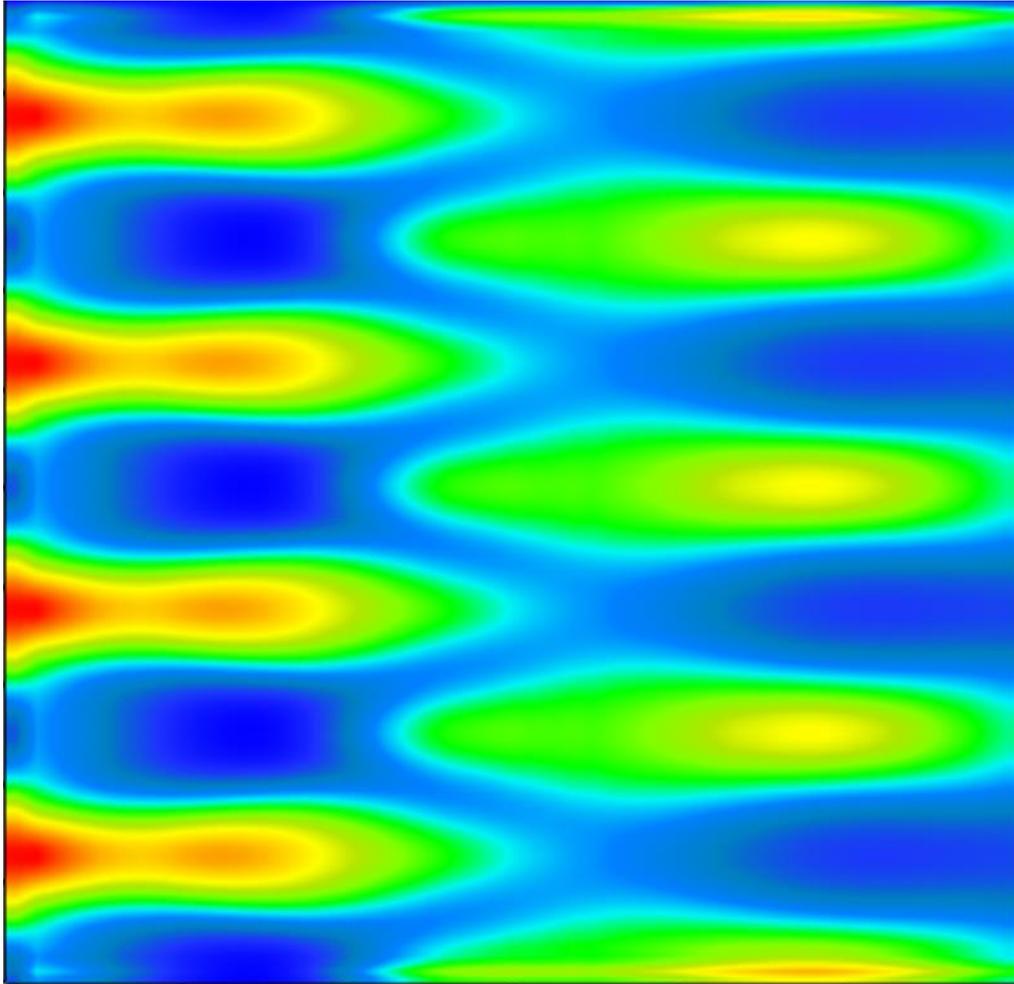


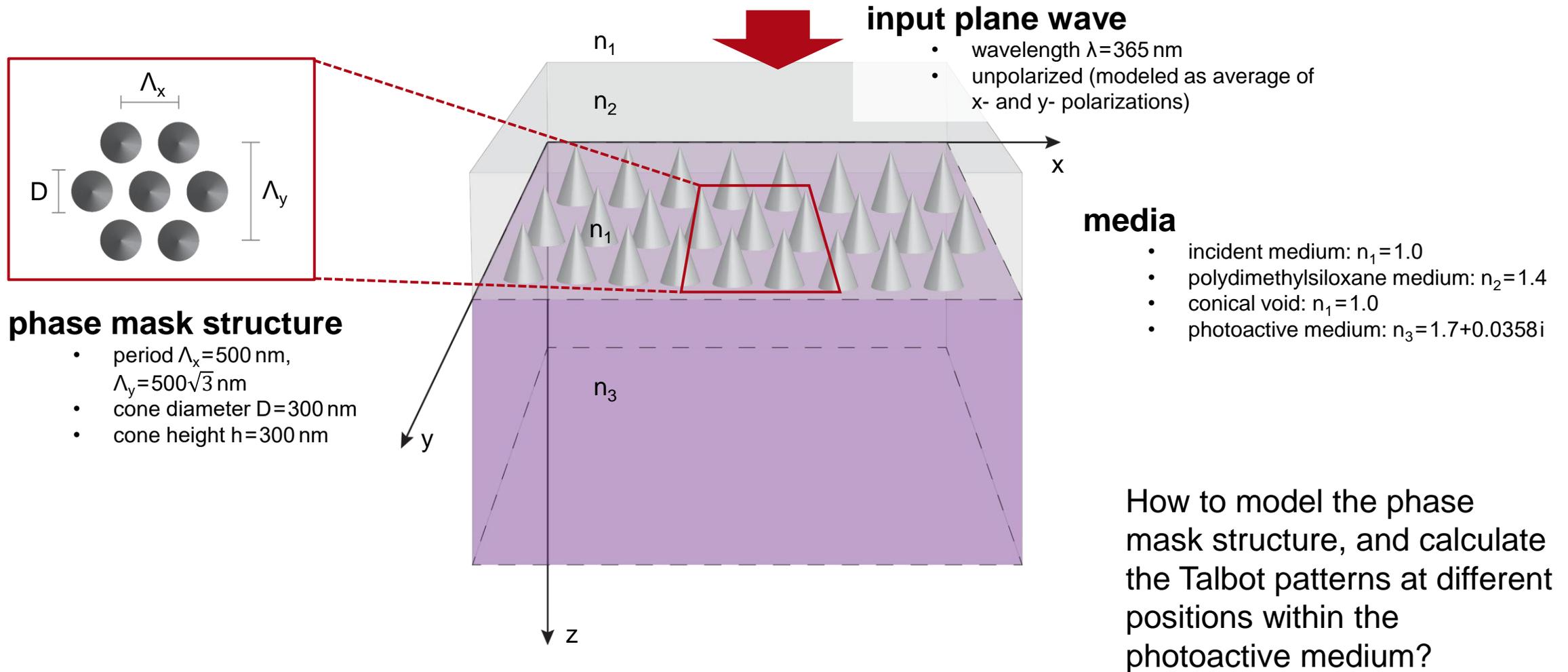
Talbot Images of A Conical Phase Mask

Abstract



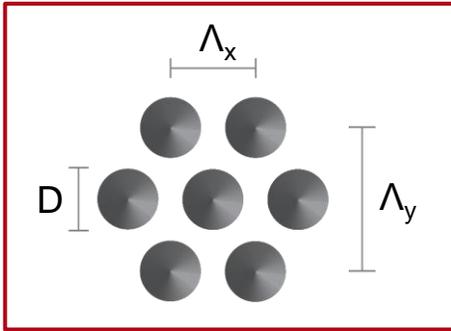
In conventional Talbot lithography, only one image is employed in the photoactive layer. However, it is possible to produce two images of the phase mask in a depth-wise manner using a special phase mask. In this example, following the work of I.-H. Lee *et al.*, a phase mask with a layer of cones is modeled in VirtualLab Fusion with the Fourier modal method (FMM, also known as RCWA). Different Talbot images are detected, such that the pillar pattern is reproduced in the primary image plane, while the hole pattern in the secondary.

Modeling Task



structure and material parameters from I.-H. Lee, *et al.*, Opt. Express 23, 25866-25873 (2015)

System Building Blocks



phase mask structure

- period $\Lambda_x = 500$ nm,
- $\Lambda_y = 500\sqrt{3}$ nm
- cone diameter $D = 300$ nm
- cone height $h = 300$ nm

The phase mask is modeled with the 2D grating component in a grating-specific optical setup, using a *Pillar Medium* sandwiched between the embedding medium and the photoresist.

Index	z-Distance	z-Position	Surface	Subsequent Medium	Com
1	0 mm	0 mm	Plane Interface	photoresist(365nm)	Enter your commen
2	120 nm	120 nm	Plane Interface	Pillar Medium (Genera	Enter your commen
3	300 nm	420 nm	Plane Interface	Non-Dispersive Mater	Enter your commen

Validity: Add Insert Delete

Periodicity & Aperture

Periodic Non-Periodic

Stack Period is Dependent from the Period of Medium with Index 2

Stack Period 500 nm × 866.0254 nm

OK Cancel Help

Embedding Material

Name Non-Dispersive Material (n=1.41)

Defined by Constant Refractive Index 1.41

State of Matter Solid

Pillar Material

Name Non-Dispersive Material (n=1)

Defined by Constant Refractive Index 1

State of Matter Solid

Pillar Geometry Pillar Distribution

Height 300 nm

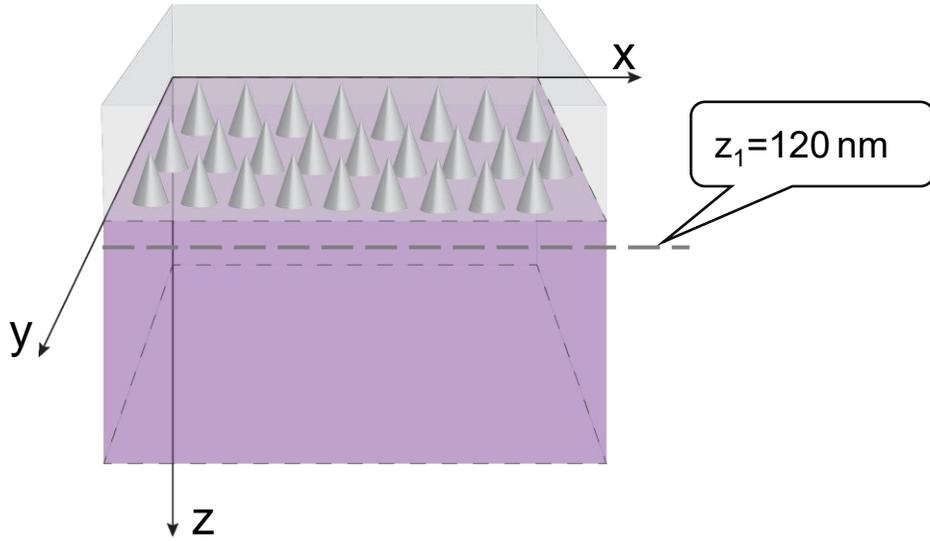
Side Wall Slope Angle 116.565°

Shape Squared Circular

Definition Mode of Diameters Bottom

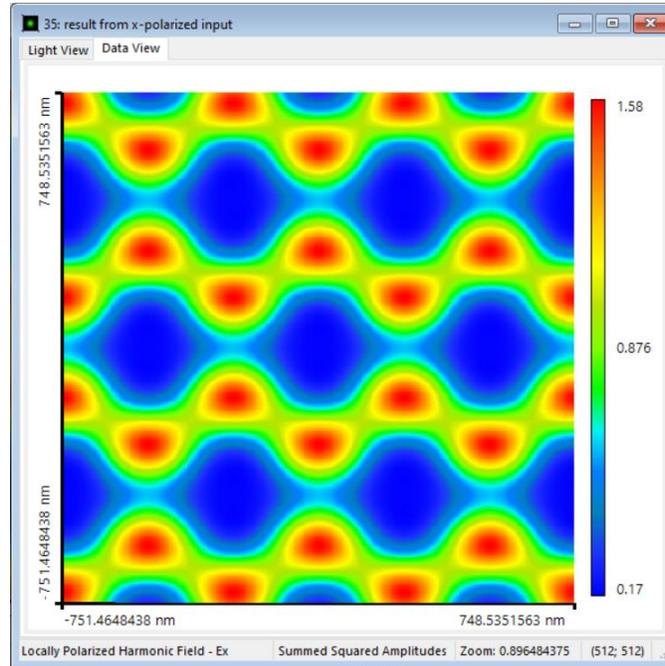
Round Edges

Talbot Pattern at a Certain Position

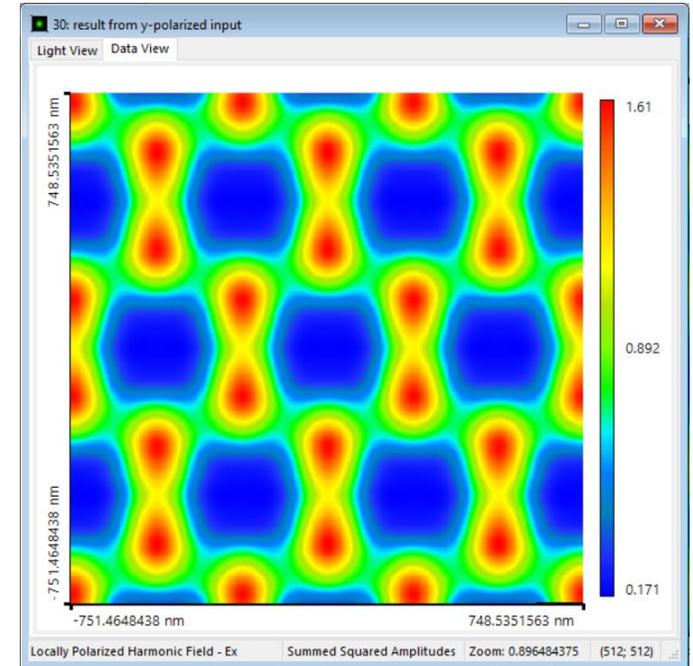


The intensity at a certain z -position is calculated separately for the input beams with different polarization states (linear x - and y -polarization).

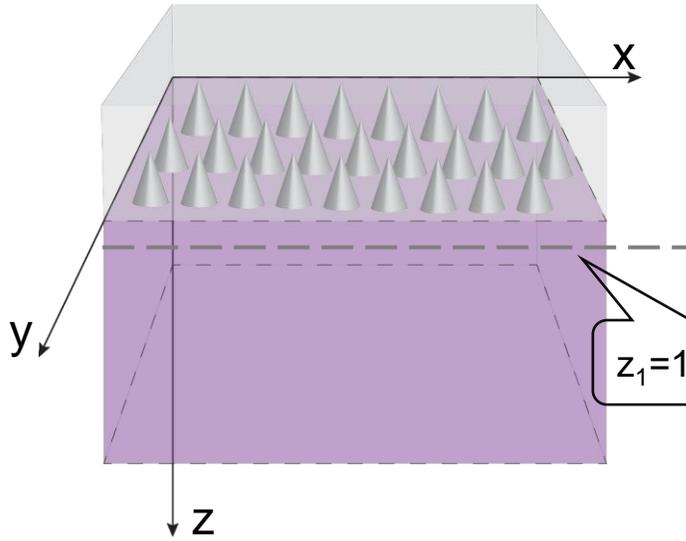
result from x-polarized input



result from y-polarized input

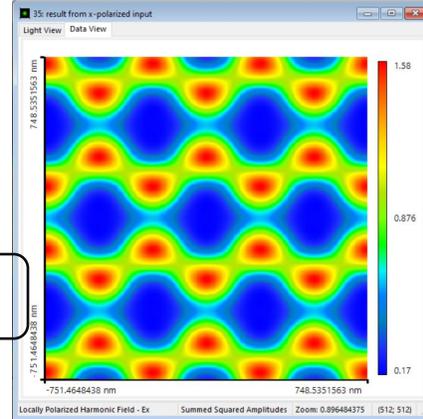


Talbot Pattern at a Certain Position

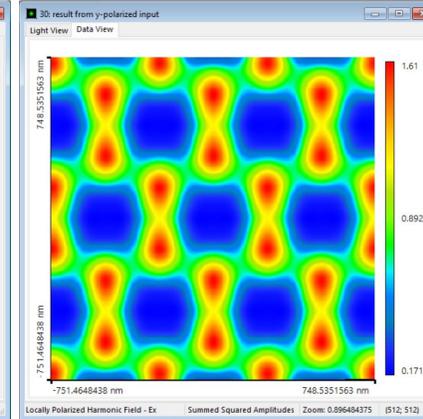


$z_1 = 120 \text{ nm}$

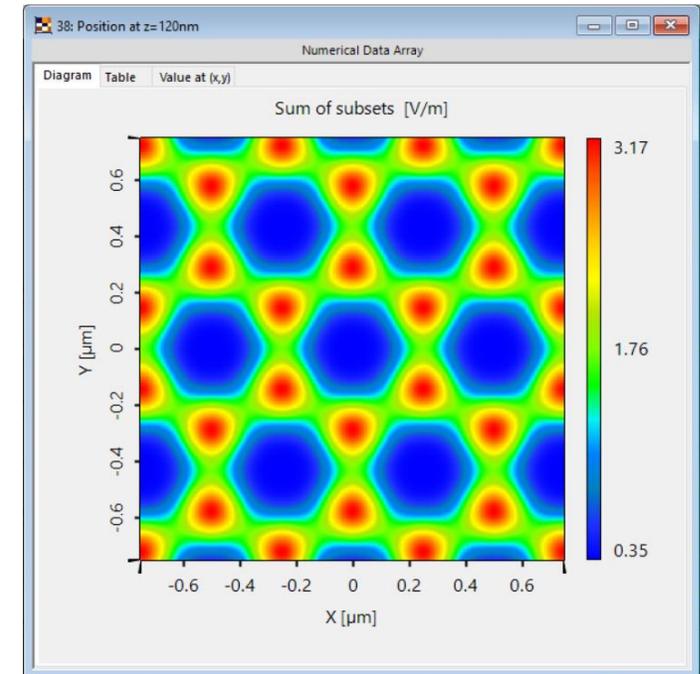
x-polarized



y-polarized

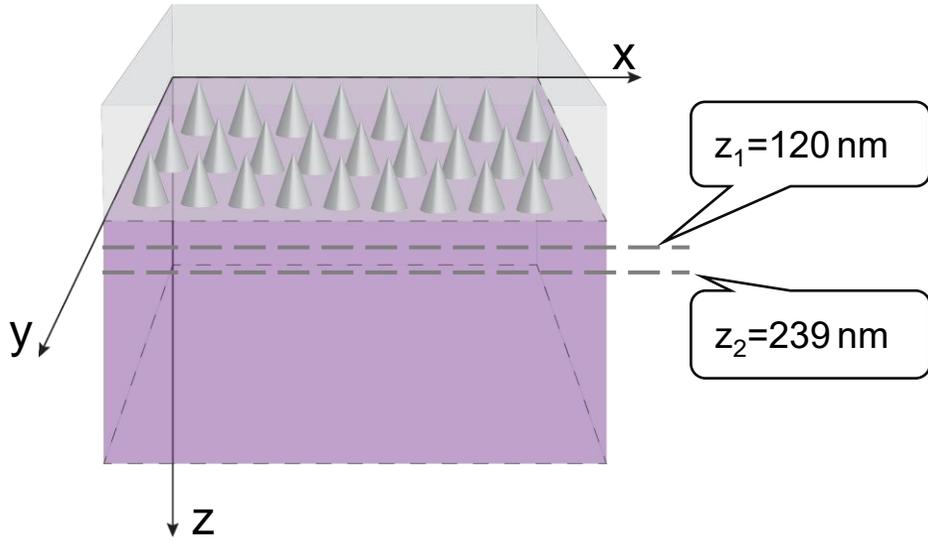


unpolarized

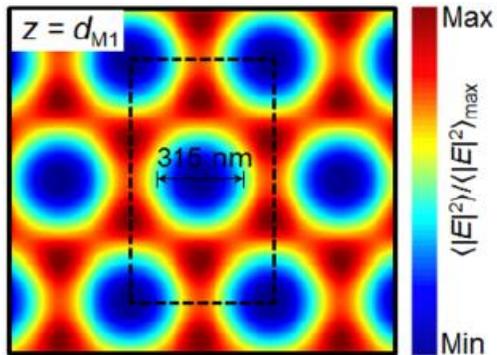
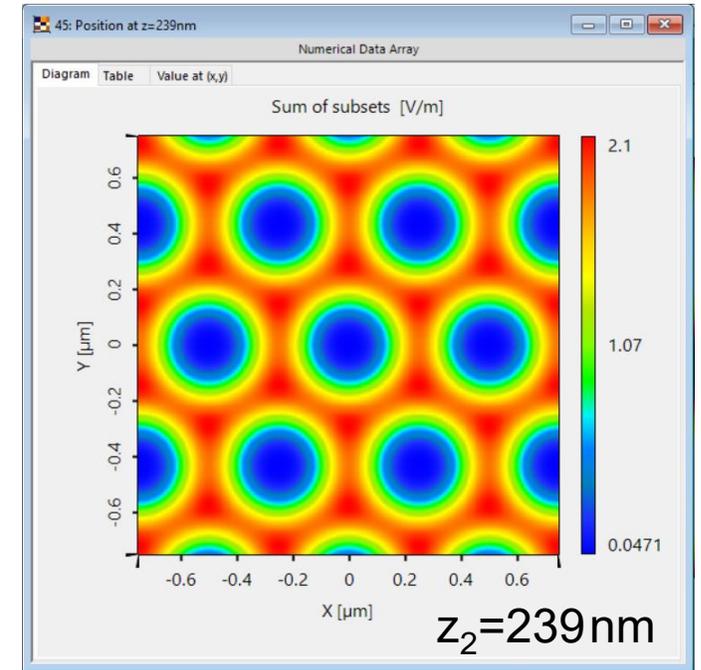
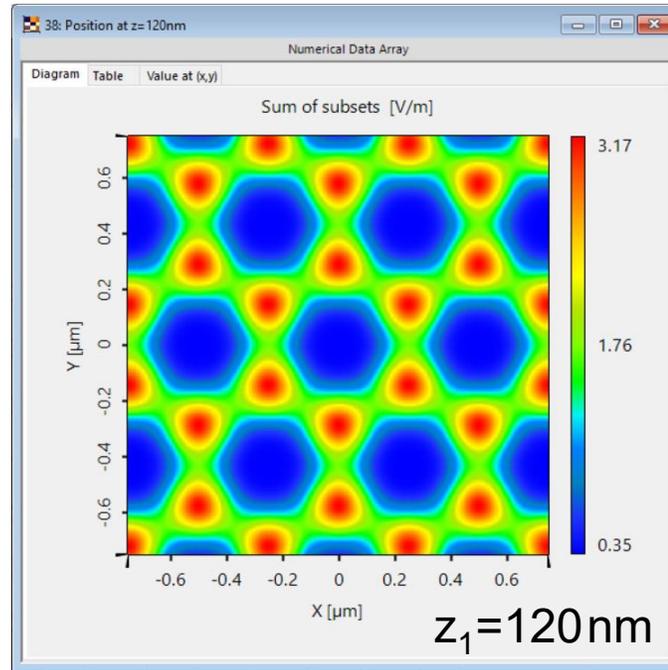


The total intensity is obtained by an incoherent average of the results from the linear x- and y-polarization states.

Talbot Pattern at Different Positions



simulation result in VirtualLab Fusion

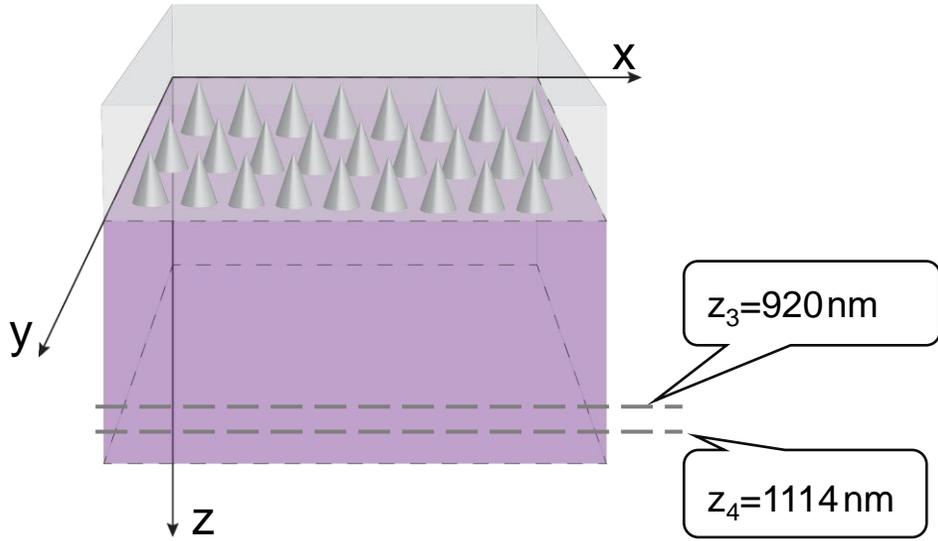


(b)

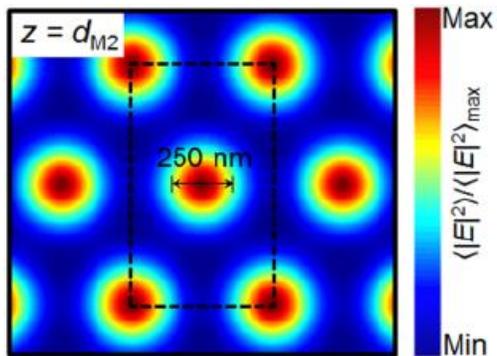
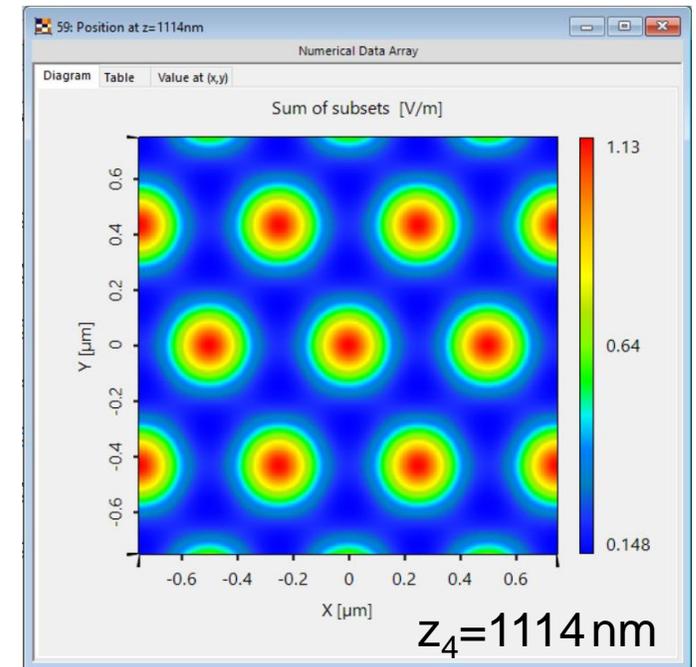
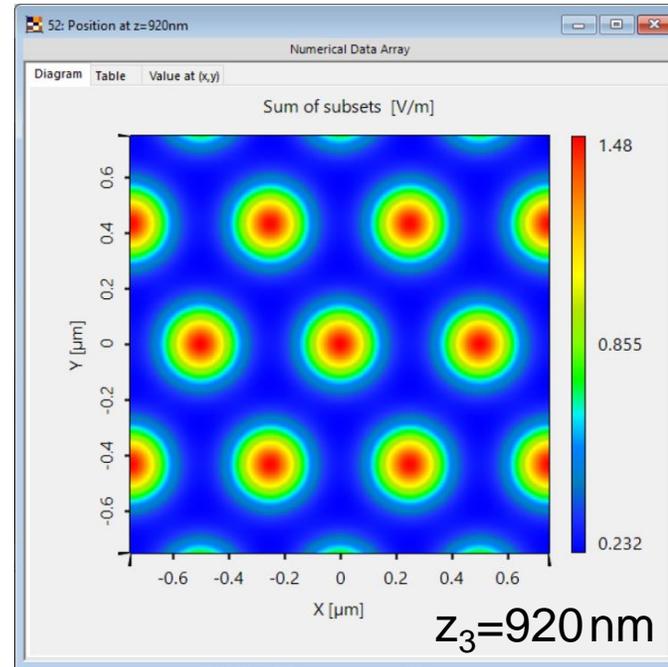
simulation result from reference:

I.-H. Lee, *et al.*, Opt. Express 23, 25866-25873 (2015). [Fig. 2 (b) $d_{M1} = 120 \text{ nm}$]

Talbot Pattern at Different Positions



simulation result in VirtualLab Fusion

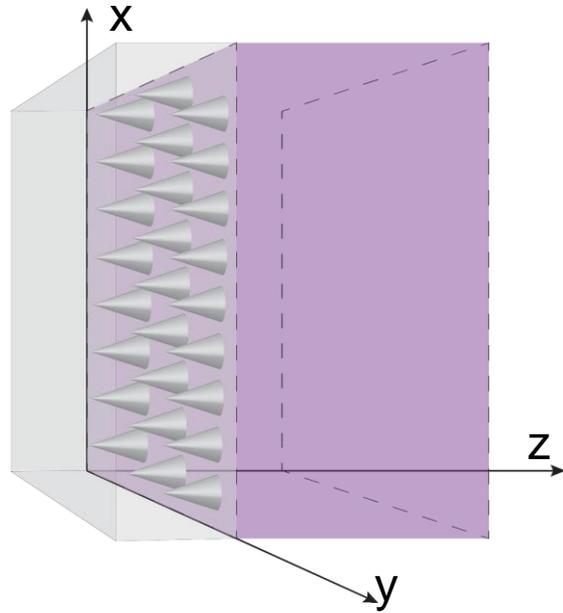


(c)

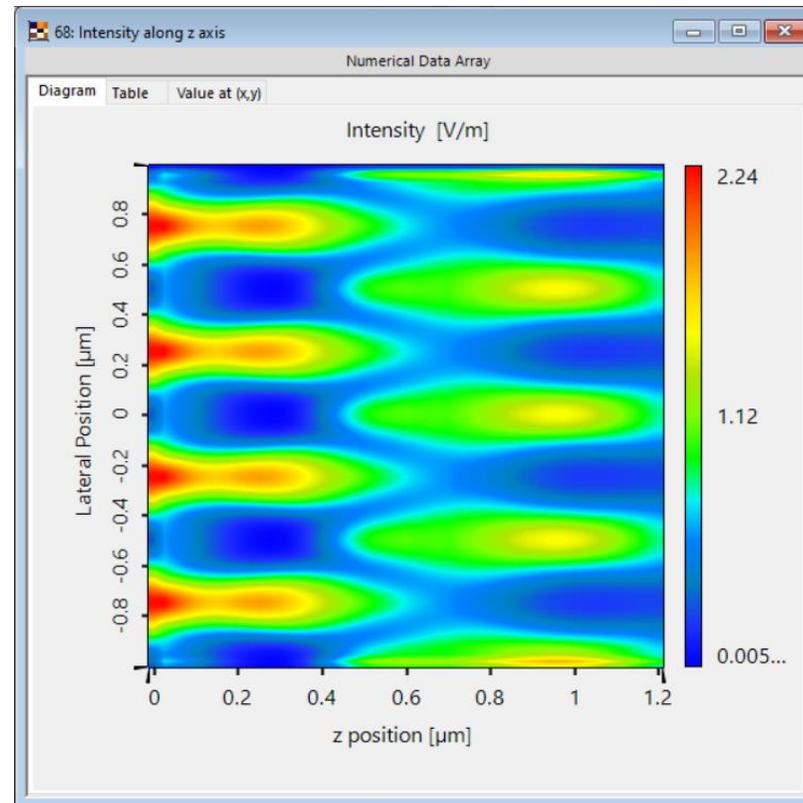
simulation result from reference:

I.-H. Lee, *et al.*, Opt. Express 23, 25866-25873 (2015). [Fig. 2 (c) $d_{M2}=920\text{nm}$]

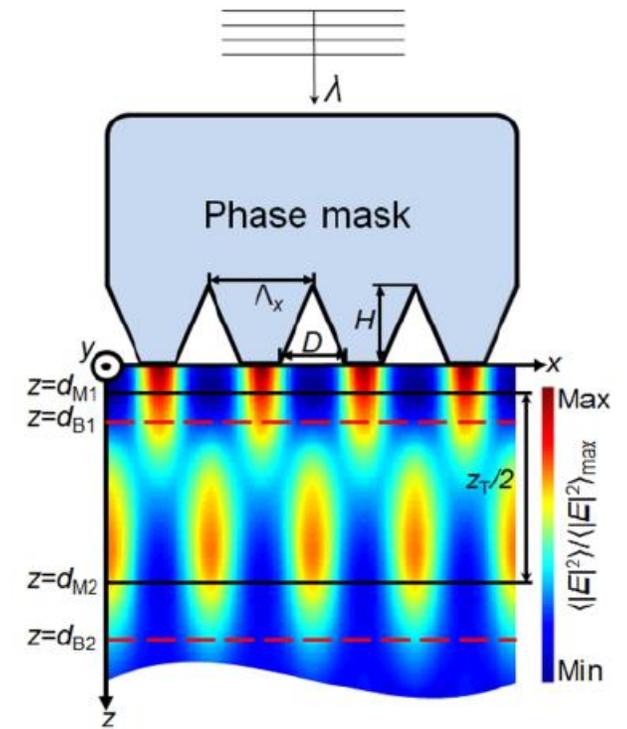
Intensity along Z-Axis



simulation result in VirtualLab Fusion

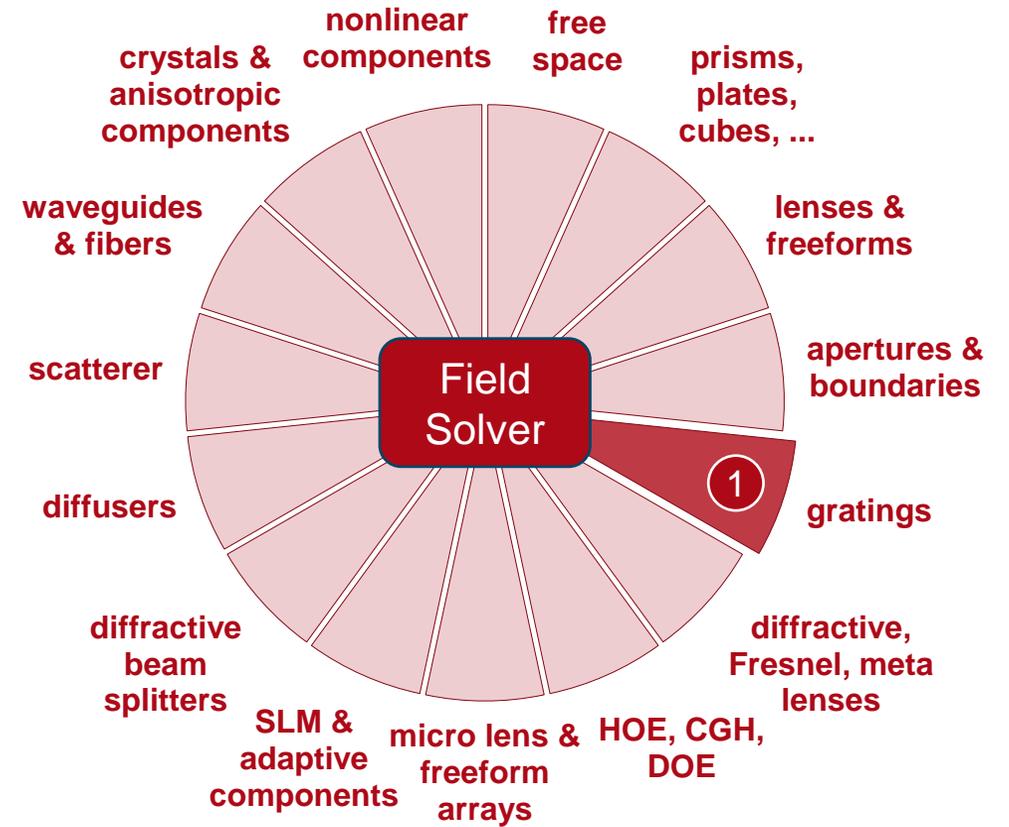
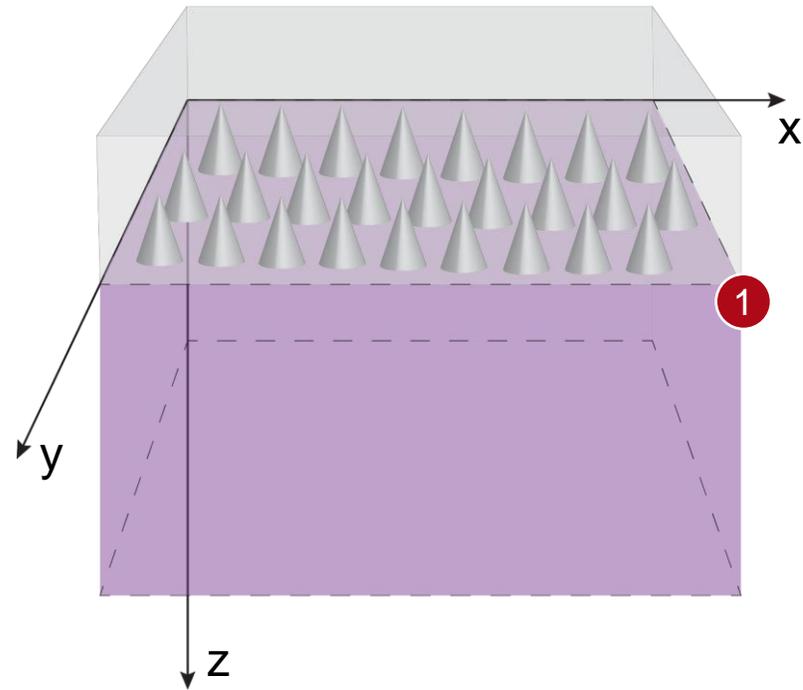


simulation result from reference:
I.-H. Lee, *et al.*, Opt. Express 23, 25866-25873
(2015). [Fig. 2 (a)]



(a)

VirtualLab Fusion Technologies



Document Information

title	Talbot Images of A Conical Phase Mask
document code	GRT.0023
document version	1.1
software edition	VirtualLab Fusion Advanced
software version	2021.1 (Build 1.180)
category	Application Use Case
further reading	<ul style="list-style-type: none">- <u>Ultra-Sparse Dielectric Nano-Wire Grid Polarizers</u>- <u>Grating Order Analyzer</u>- <u>Modeling of the Talbot Effect</u>- <u>Configuration of Grating Structures by Using Interfaces</u>- <u>Configuration of Grating Structures by using Special Media</u>